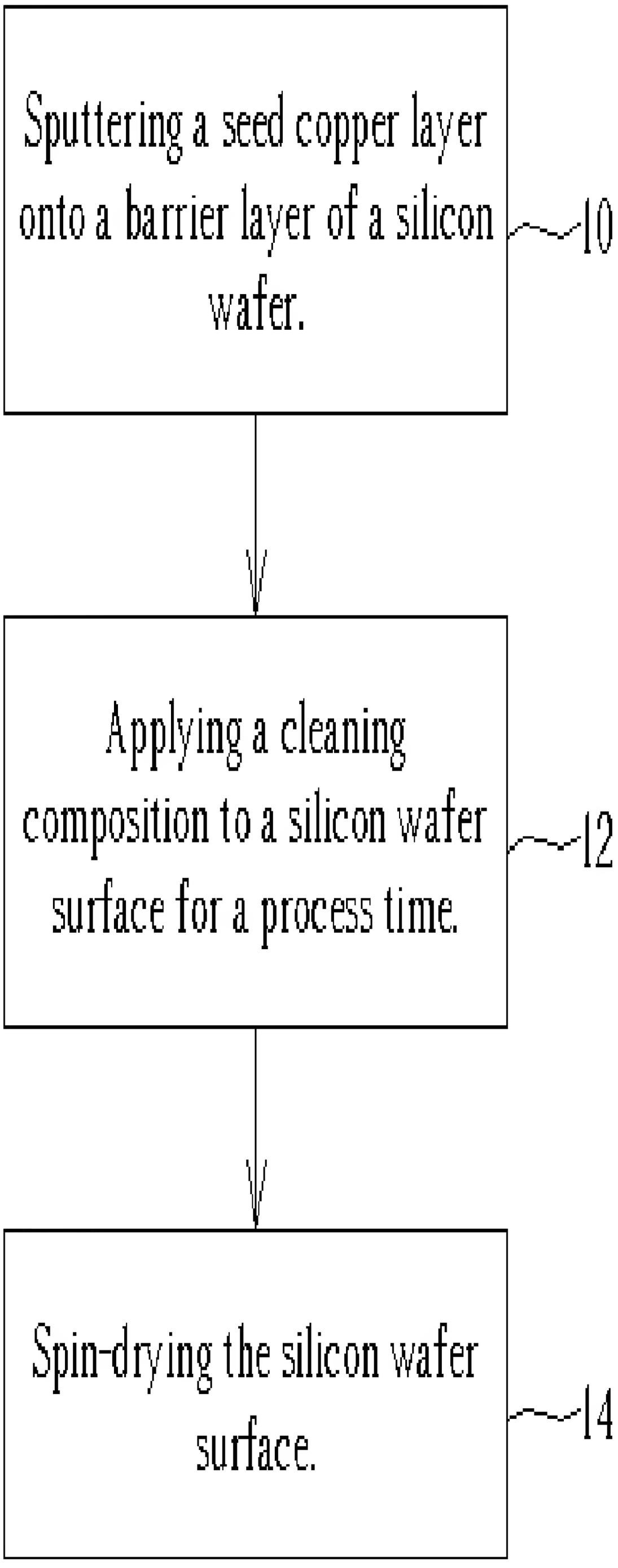
Sputtering a seed copper layer onto a barrier layer of a silicon wafer.
10
Applying a cleaning composition to a silicon wafer surface for a process time.
12
Spin-drying the silicon wafer surface.
14

Fig. 1